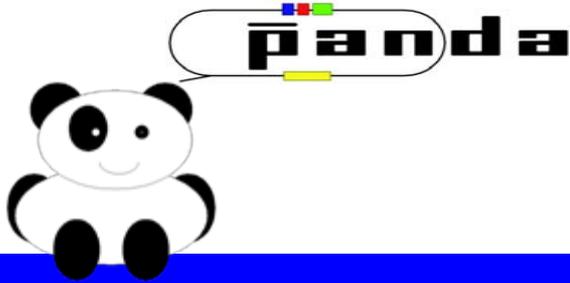


## Hybrid pixel detector in the PANDA experiment



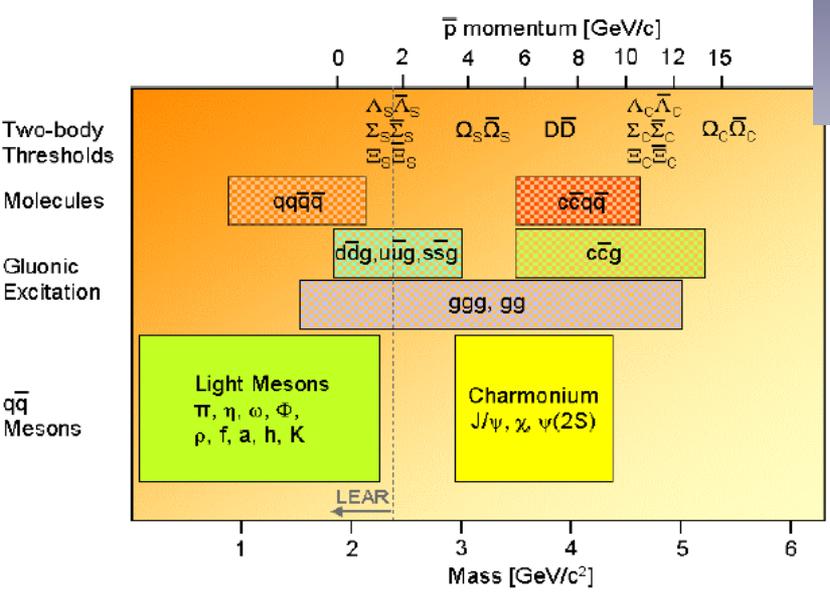
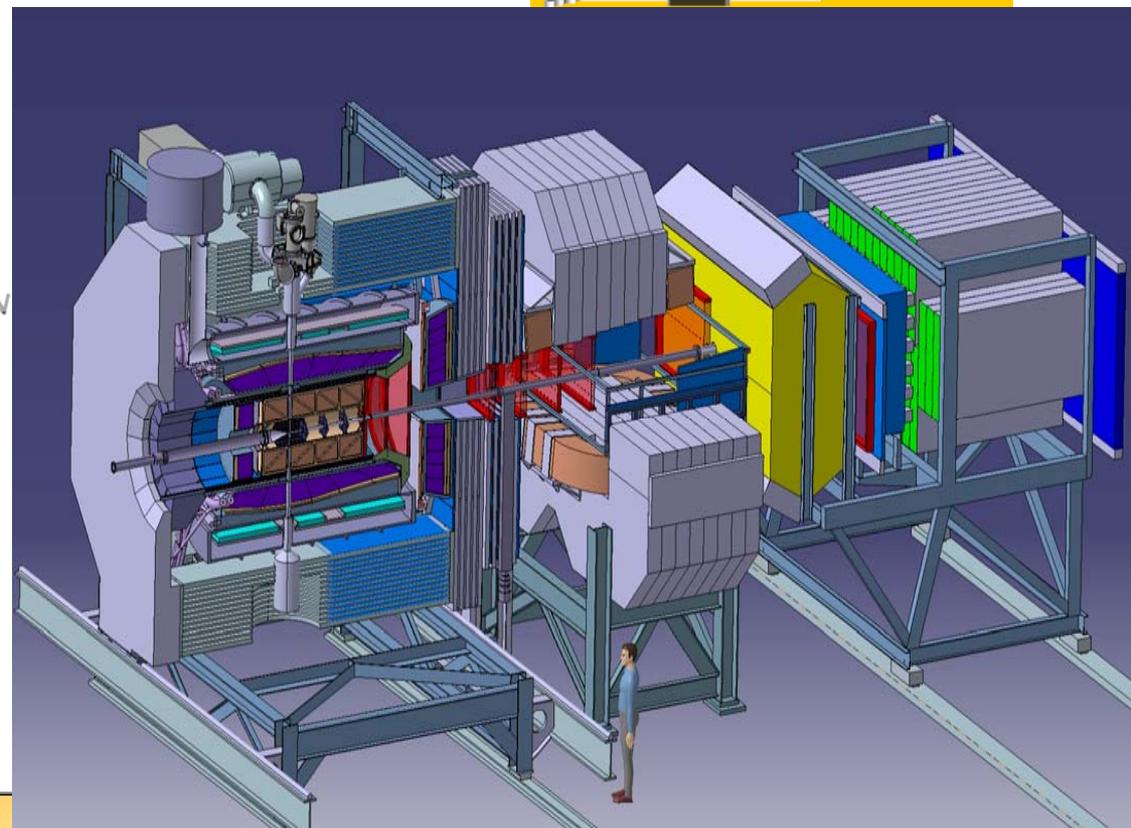
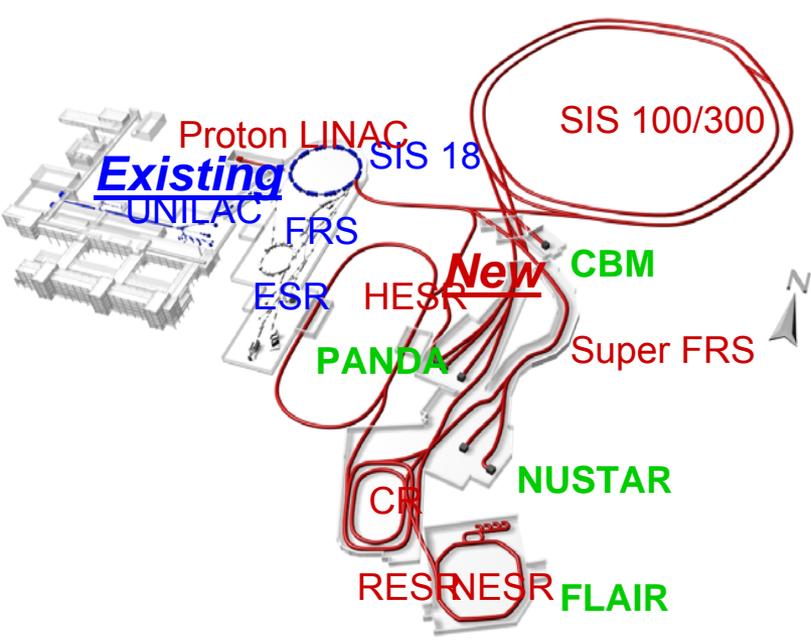
D. Calvo, S. Coli, P. De Remigis, G. Giraudo,  
T. Kugathasan, G. Mazza, A. Rivetti, R. Wheadon  
(INFN-Torino)  
in the PANDA Collaboration

RD09 – 9° International Conference on Large Scale Applications  
and Radiation Hardness of Semiconductor Detectors  
Firenze, 30 September – 2 October 2009



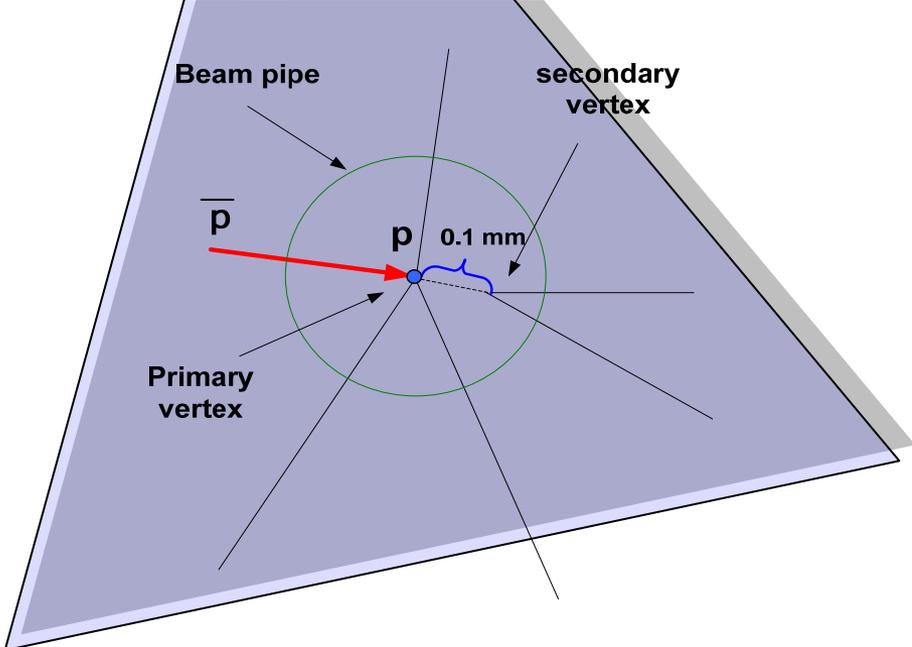
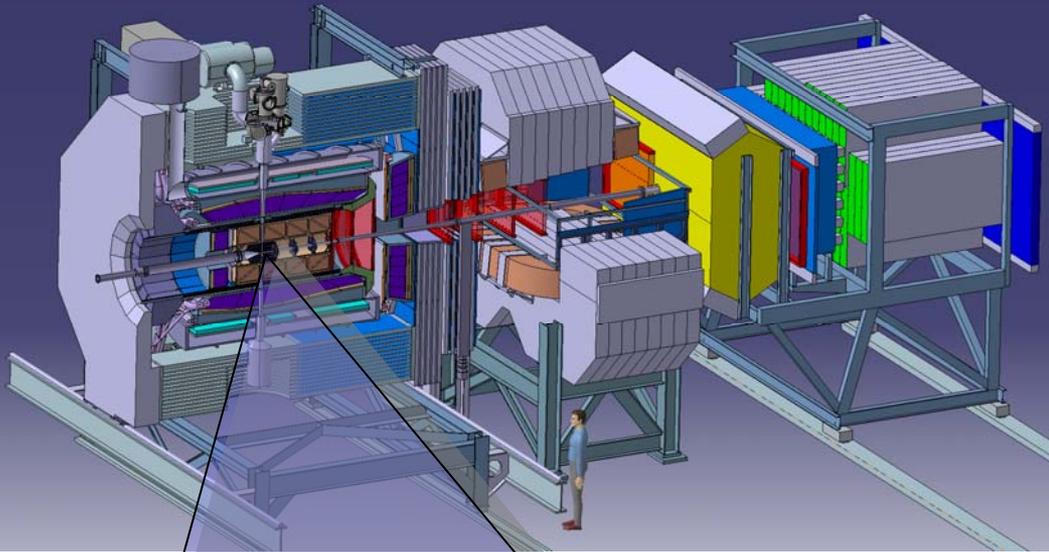
## Overview

- Introduction – the MVD in PANDA
- Custom hybrid pixel detector
  - detector layout and cooling system
  - epitaxial silicon devices - results
  - pixel readout prototype - results
- Conclusion



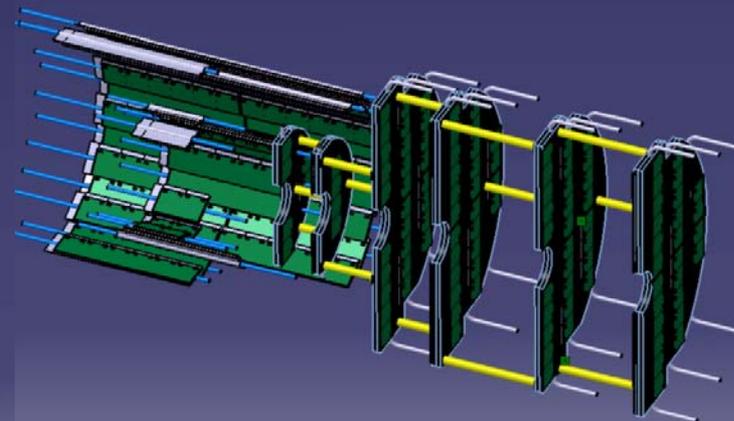
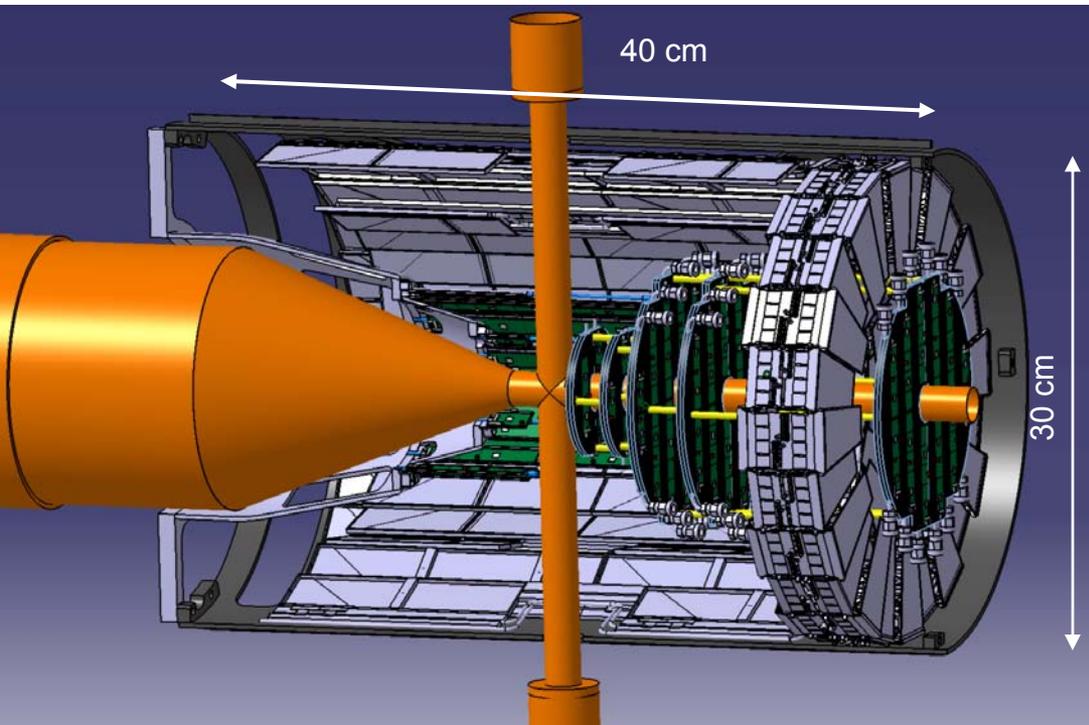
- Nearly  $4\pi$  solid angle
- High rate capabilities ( $2 \cdot 10^7$  annihilations /s)
- Continuous readout and Efficient event selection
- Moment resolution (1%)
- Vertex info for D,  $K_S^0$ , L ( $c_\tau = 317 \mu\text{m}$  for  $D^{+-}$ )
  - good tracking
- Good PID ( $\gamma$ , e, m,  $\pi$ , k, p) with Cherenkov, tof, dE/dx

# Micro-Vertex-Detector requirements



- Good spatial resolution in r-phi
  - Momentum measurement of pions from  $D^*$  decays
- Good spatial resolution specially in z
  - Vertexing, D-tagging
- Good time resolution
  - $\leq 10 \text{ ns}$
  - with  $2 \cdot 10^7 \text{ ann/s}$
- Triggerless readout
- Energy loss measurement
  - $dE/dx$  for PID
- Low material budget
  - low momentum of particles (from some hundreds of  $\text{MeV}/c$ )
  - ( $< 1\% X_0$  for each layer)
- Radiation hardness ( $\sim 4 \cdot 10^{13} \text{ n}_{1\text{MeV eq}}/\text{cm}^2$ ) (half year data taking,  $15 \text{ GeV}/c$  antip-p)
  - Different radiation load

# MVD layout



## Micro Vertex Detector

4 barrels

*Inner layers:* hybrid pixels

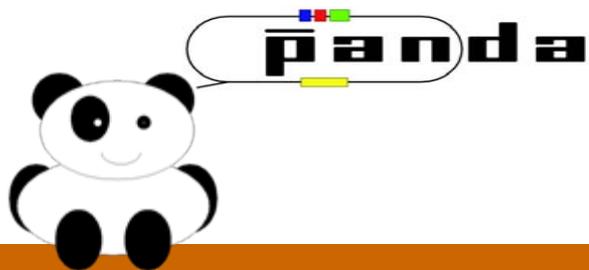
*Outer layers:* double sided strips  
and 6 forward disks

*4 disks:* hybrid pixels

*2 disks:* pixel and strips mixed

## Custom Pixel Detector:

- Hybrid pixel made by thin epitaxial sensors and readout with 130 nm CMOS technology
- 100  $\mu\text{m}$  x 100  $\mu\text{m}$  pixel sizes;
- ~ 850 FE readout chip (12760 pixels);
- continuous data transmission without trigger
- max. chip data rate : ~ 0.8 Gb/s (40 bit/pixel)
- energy loss measurement: time over threshold; dynamic range:  $\rightarrow$  100 fC



# Hybrid pixel detector layout

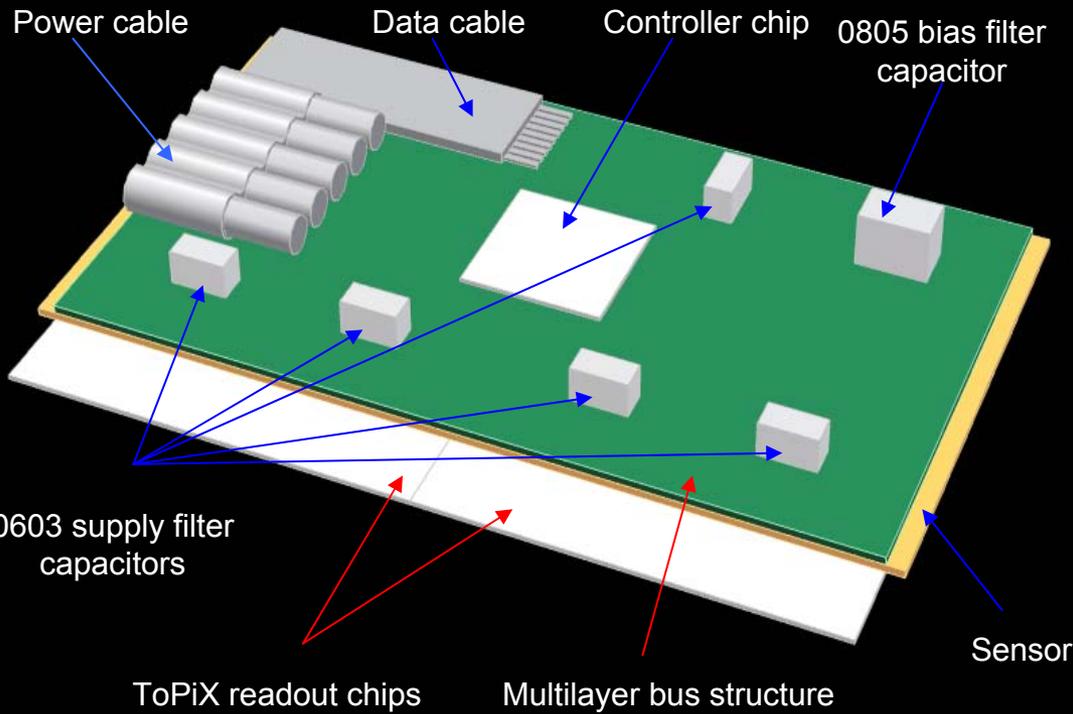
D. Calvo



# Assembly layout on the disks

## Assembly scheme

### 2-readout chip module

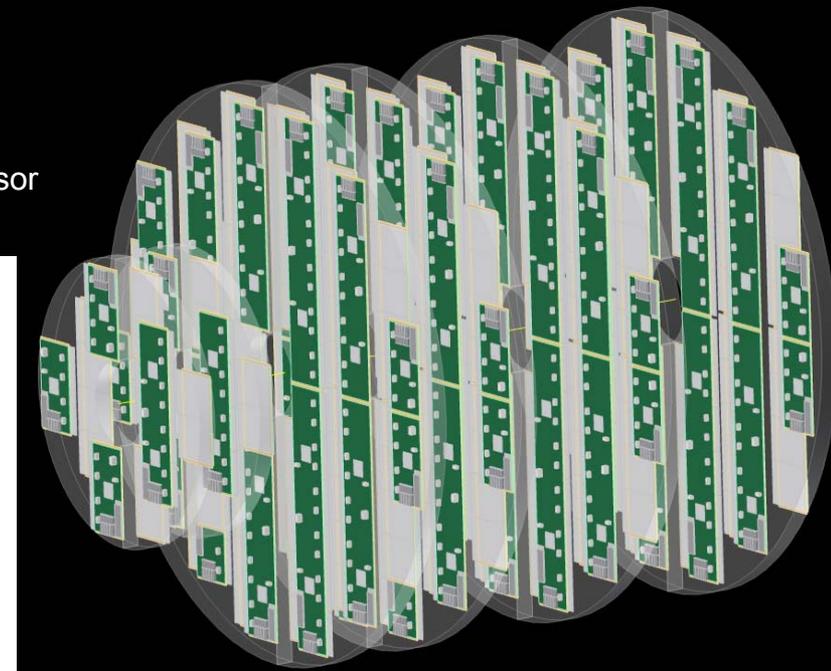


- Controller chips serve two or three ToPiX readout chips

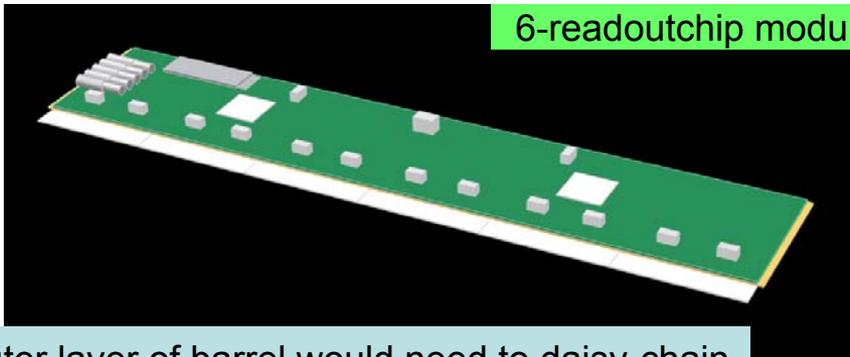
Possibility of daisy-chaining controllers to save on cables (where data rates allow)

Keeping cables out of active region means that some modules may require two designs according to which end the cables have to be connected

## Layout of forward disks

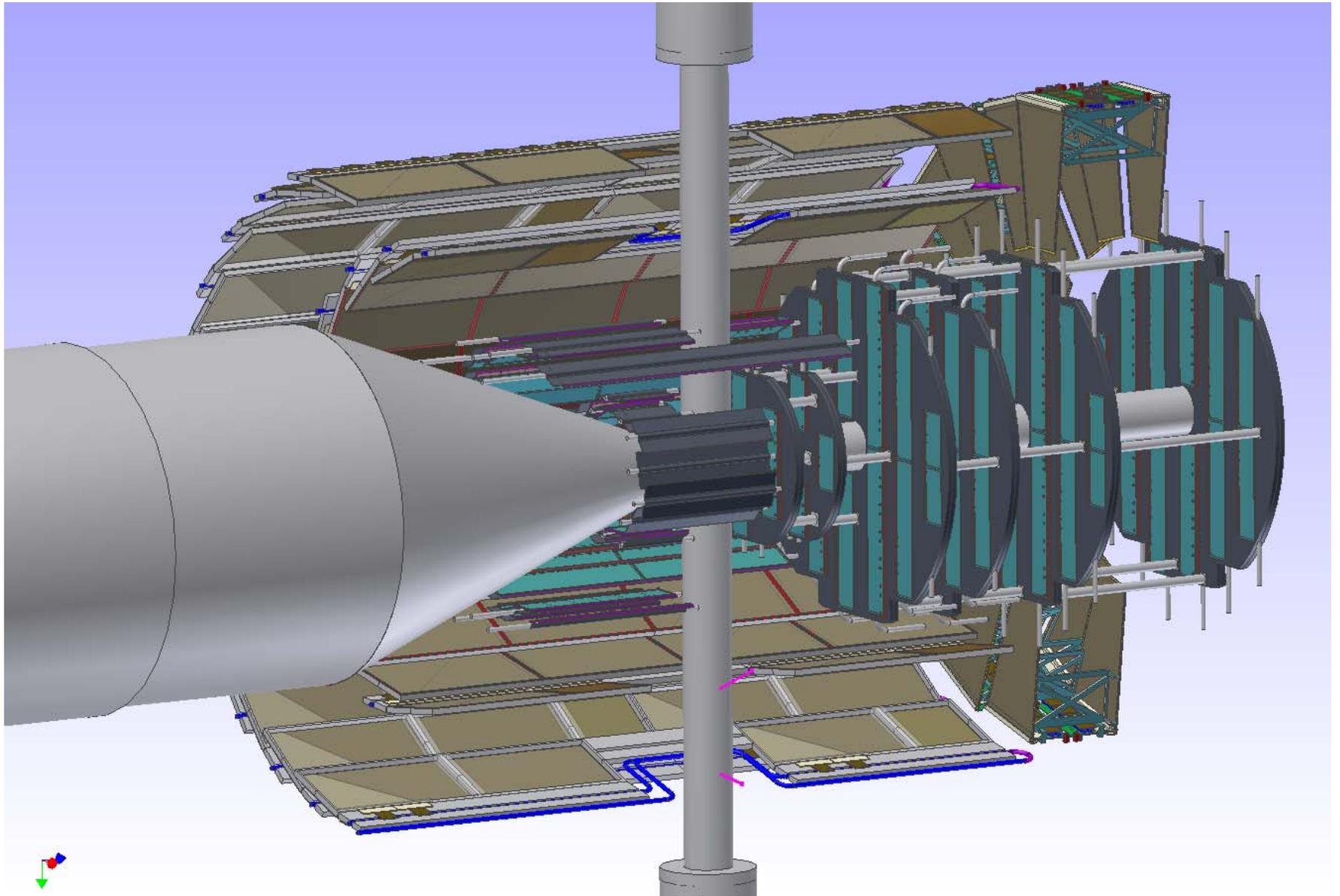


### 6-readout chip module

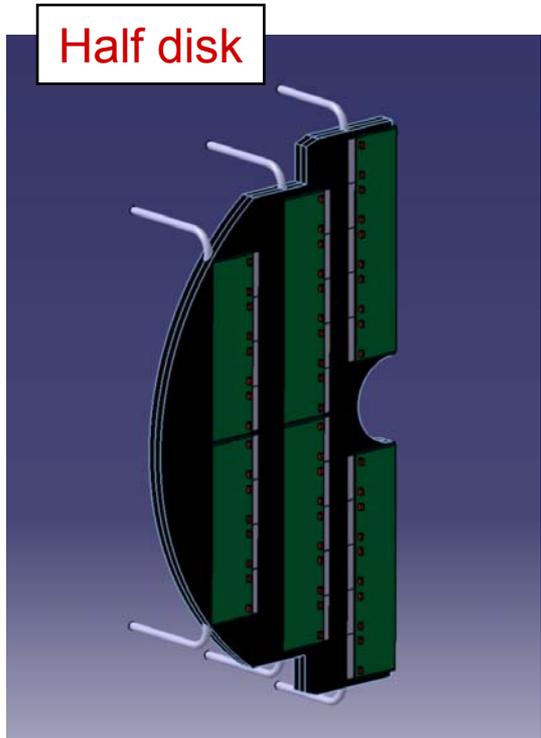


For outer layer of barrel would need to daisy-chain two 6-chip modules (power and controller chips) to keep cables out of active region

# Pixel detector scheme



# Disk and stave layout



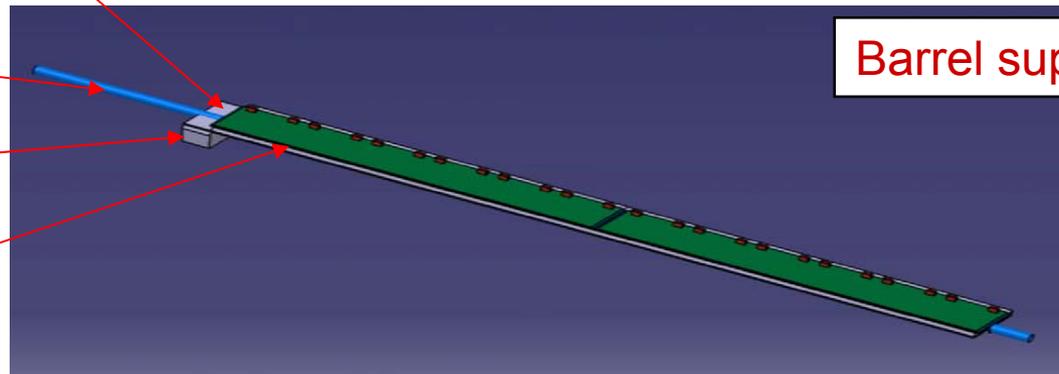
- Disk split in two halves along the mid-plane
- Material for heat dissipation/support: carbon foam
- Embedded cooling capillary between the two halves
- All elements glued with thermal glue
- Problem: large glued area -> test have to be performed

“Omega” support (CFRP – thermal & structural)

cooling capillary

reference block

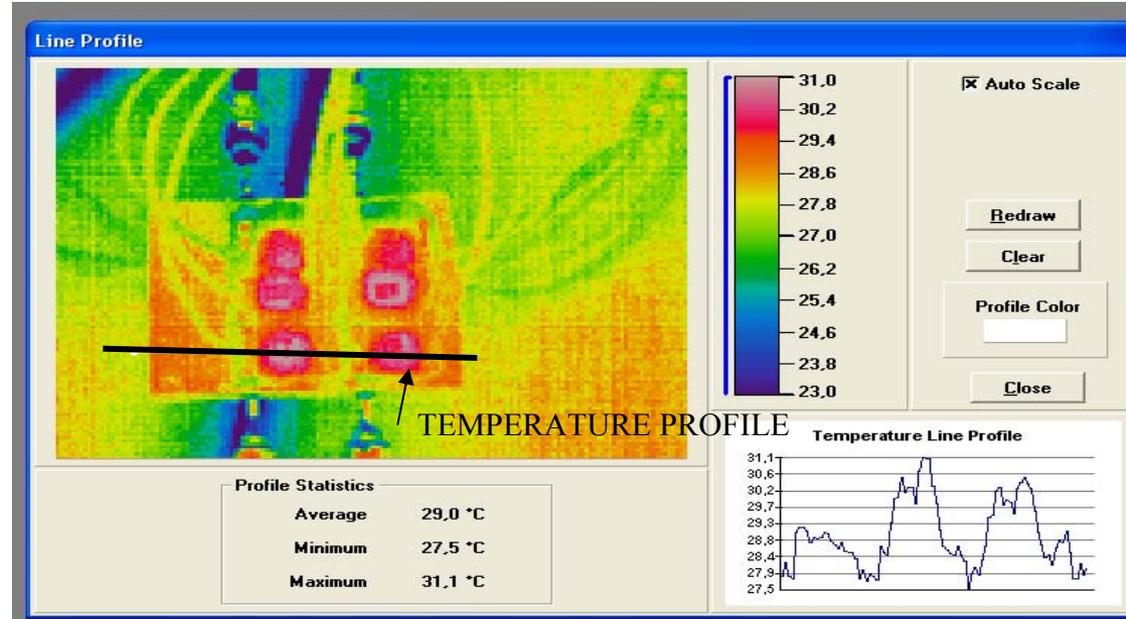
foam substrate



Barrel super-module

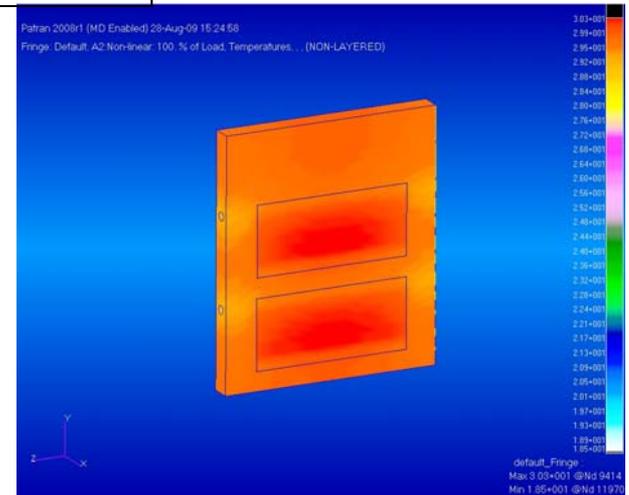
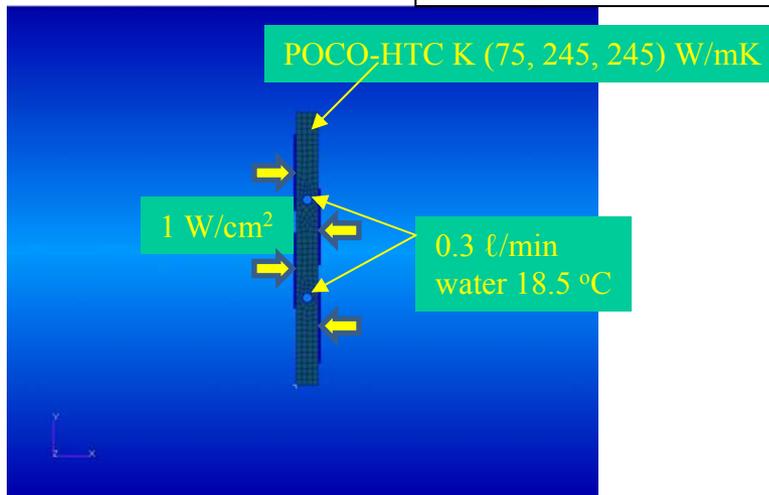
# First study on water cooling system

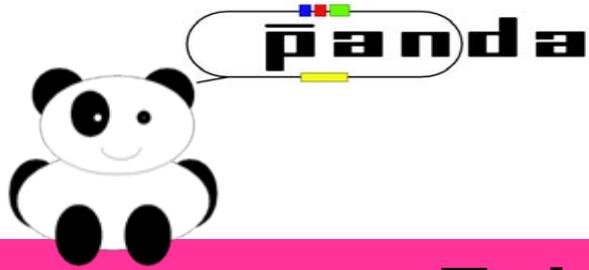
Small and partial prototype of a disk  
Cooling fluid: water @ 18.5 °C  
12 resistors (1 W/cm<sup>2</sup> each resistor)  
POCO-HTC foam support (4 mm thick)  
Stainless steel pipes ( $\phi_e$ 2mm,  $\phi_i$ 1.84mm)



Cooling test results – IR image

Results from simulations





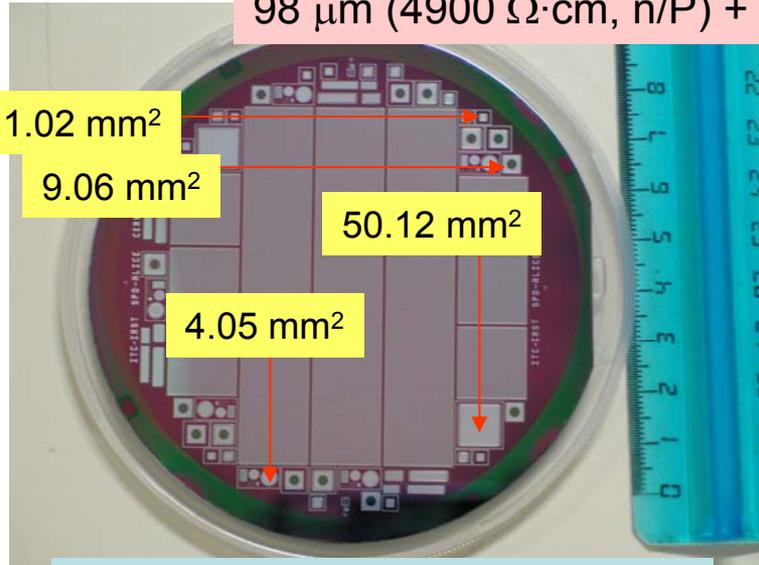
# Epitaxial silicon devices

D. Calvo



# Diodes and single chip sensor from epi-wafers

49  $\mu\text{m}$  (4060  $\Omega\cdot\text{cm}$ , n/P) + 500  $\mu\text{m}$  Cz substrate (0.01-0.02  $\Omega\cdot\text{cm}$ , n<sup>+</sup>/Sb) → 100  $\mu\text{m}$   
74  $\mu\text{m}$  (4570  $\Omega\cdot\text{cm}$ , n/P) + 500  $\mu\text{m}$  Cz substrate (0.01-0.02  $\Omega\cdot\text{cm}$ , n<sup>+</sup>/Sb) → 120  $\mu\text{m}$   
98  $\mu\text{m}$  (4900  $\Omega\cdot\text{cm}$ , n/P) + 500  $\mu\text{m}$  Cz substrate (0.01-0.02  $\Omega\cdot\text{cm}$ , n<sup>+</sup>/Sb) → 150  $\mu\text{m}$



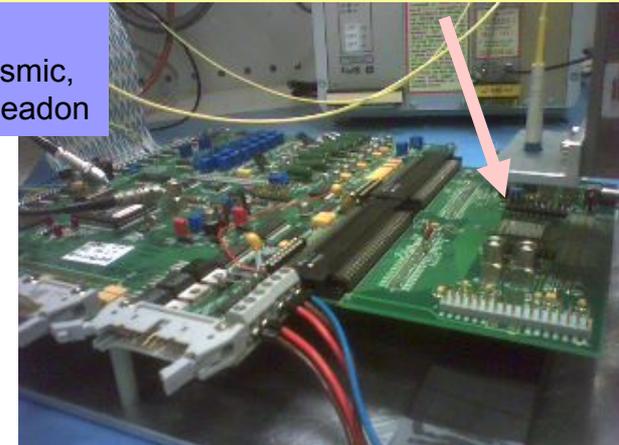
with the ALICE layout at FBK

300  $\mu\text{m}$  FZ diodes have been used as reference

## Single chip assembly

- ✓ pixel obtained with the ALICE masks (50  $\mu\text{m}$  x 425  $\mu\text{m}$ )
- ✓ test performed using ALICE pixel readout chip and test system in collaboration with P. Riedler - CERN

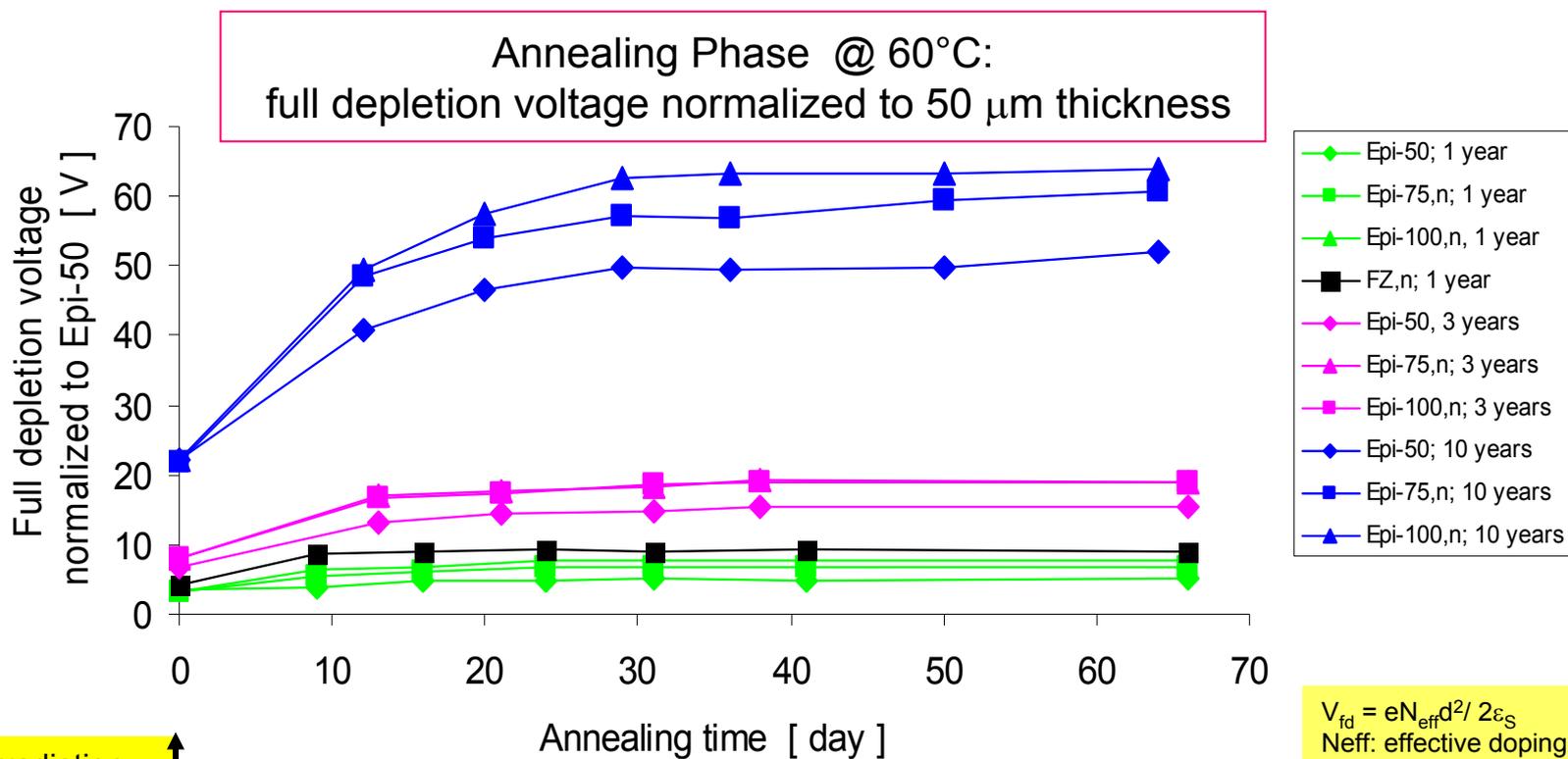
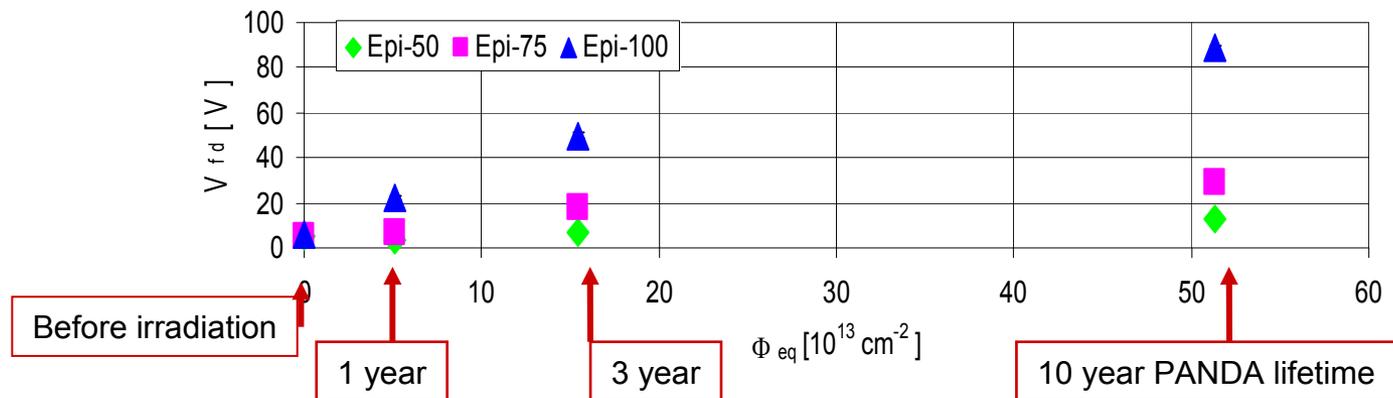
NIM A594 (2008) 29-32;  
D. Calvo, P. De Remigis, F. Osmic,  
P. Riedler, G. Stefanini, R. Wheadon



## Diodes

Test of radiation damage with neutrons from Pavia nuclear reactor. Equivalent fluence values on the diodes :  
5.13x10<sup>13</sup>, 1.54x10<sup>14</sup>, 5.13x10<sup>14</sup> n(1MeV<sub>eq</sub>)/cm<sup>2</sup>  
corresponding to ~ 1, 3 and 10 years of PANDA lifetime

# Results from radiation damage test with neutrons



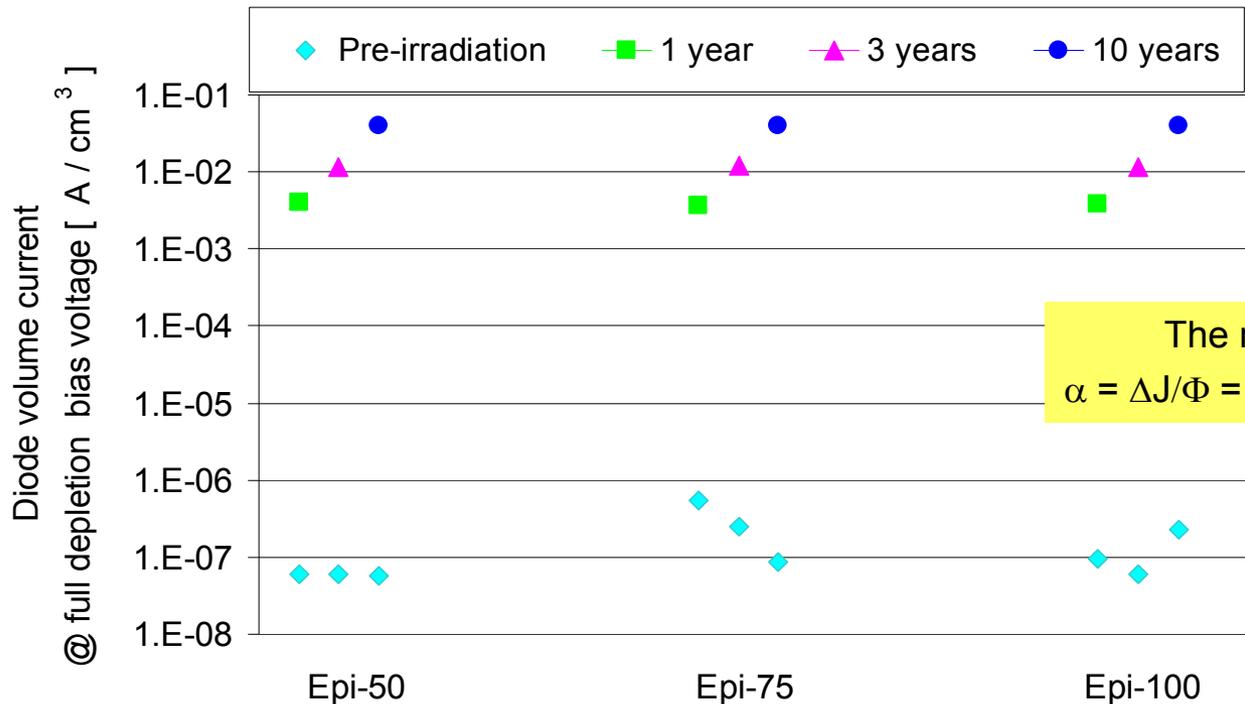
After irradiation,  
before annealing

$$V_{fd} = eN_{eff}d^2 / 2\epsilon_S$$

$N_{eff}$ : effective doping concentration  
 $d$ : diode thickness  
 $\epsilon_S$ : silicon dielectric constant

# Results from radiation damage test: the radiation damage constant

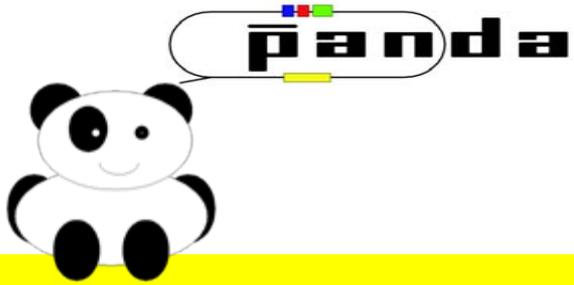
Equivalent fluence values on the diodes :  $5.13 \times 10^{13}$ ,  $1.54 \times 10^{14}$ ,  $5.13 \times 10^{14} n(1\text{MeV}_{\text{eq}})/\text{cm}^2$  corresponding to 1, 3 and 10 years of PANDA lifetime



The radiation damage constant is  
 $\alpha = \Delta J / \Phi = 7.6(\pm 0.3) \times 10^{-17} \text{ A/cm}$  for all diodes.

Lekage current < 50 nA/pixel (100  $\mu\text{m} \times 100 \mu\text{m}$  size, 100  $\mu\text{m}$  thick)

The diode volume current @ full depletion voltage, after a 65 days annealing phase @ 60°C, decreased by a factor 2.



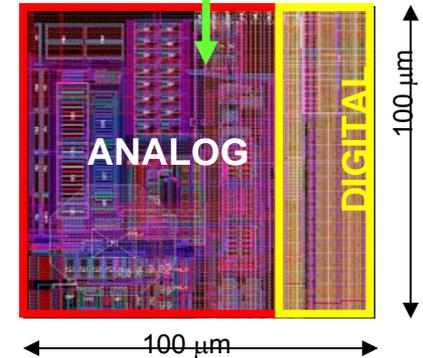
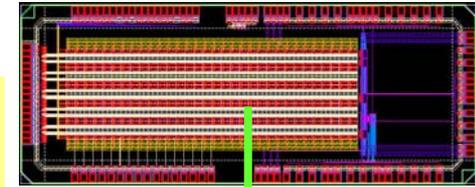
# ASIC prototype

D. Calvo

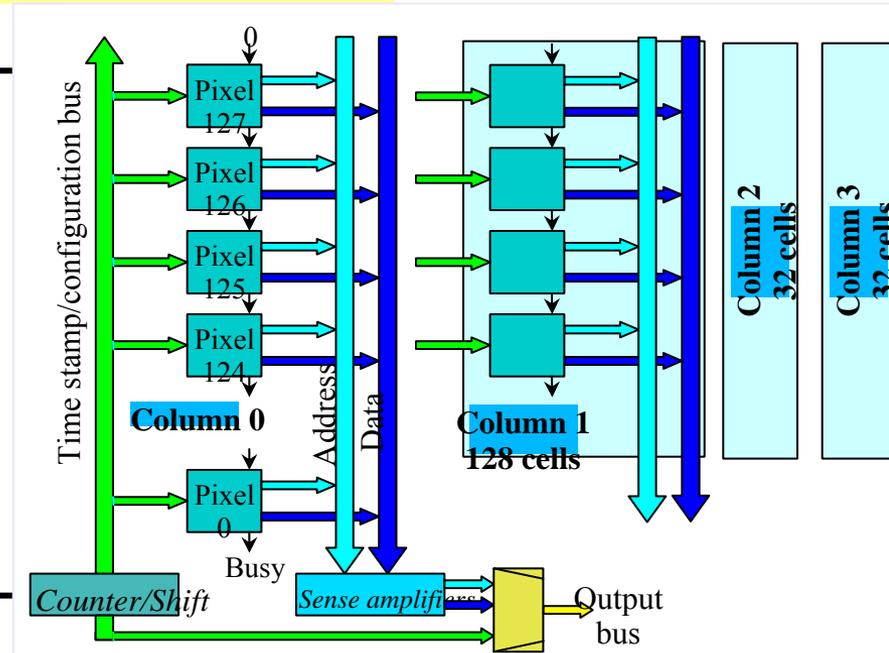
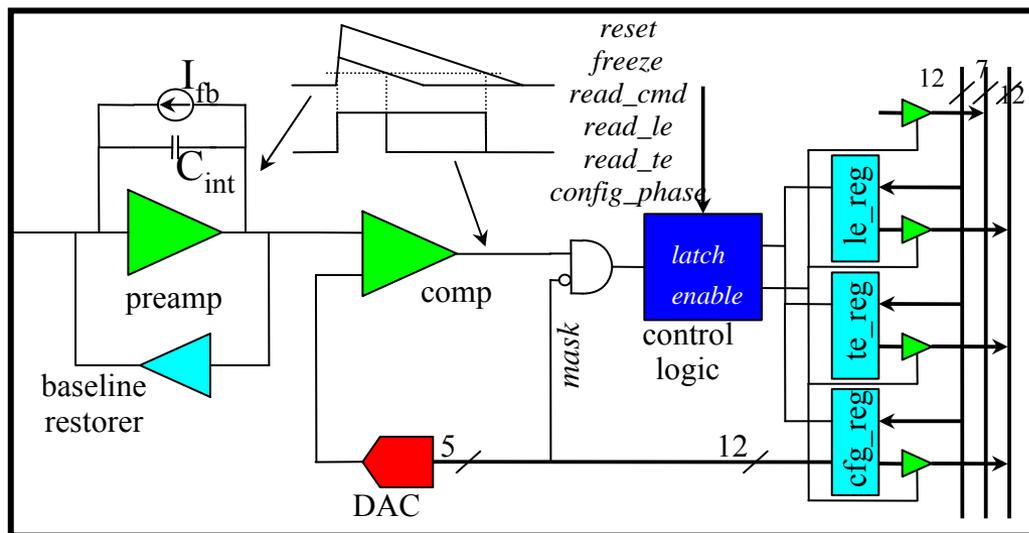


# The architecture of ToPix\_2

## ToPix\_2, 130 nm CMOS technology

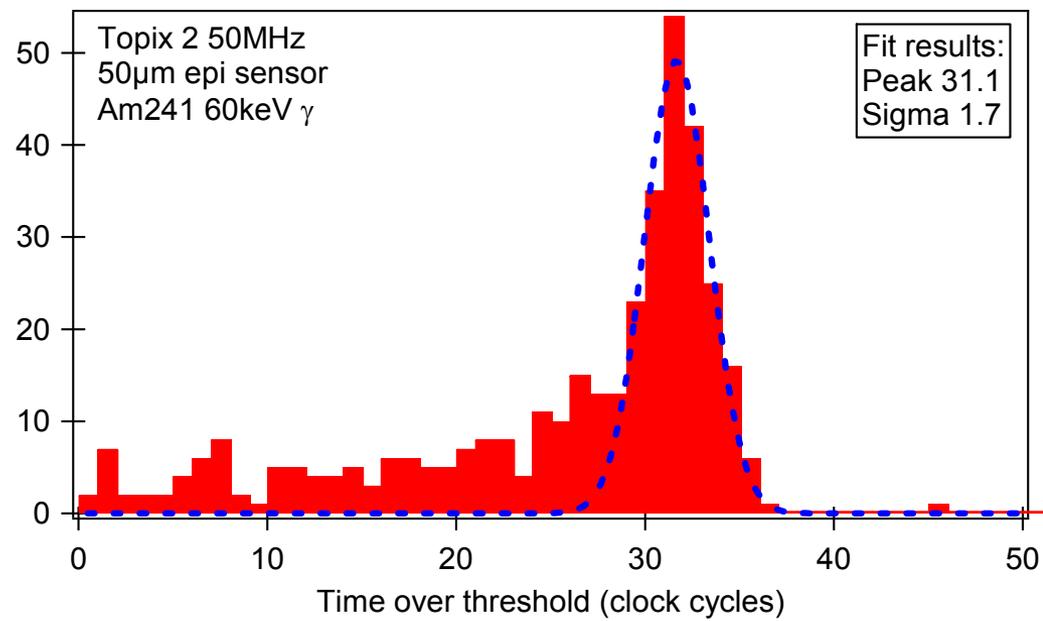
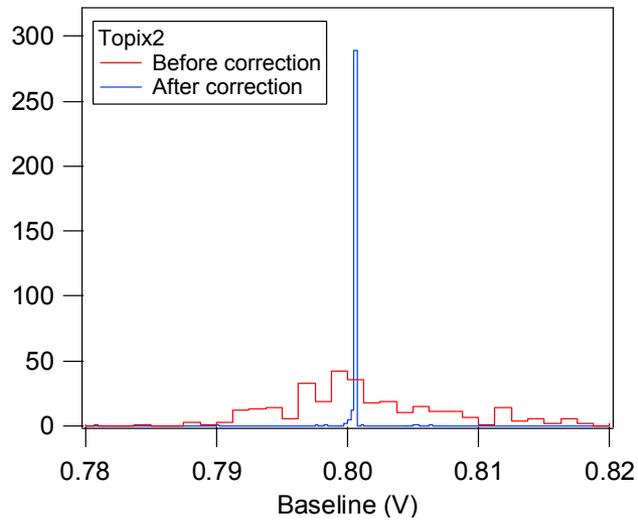
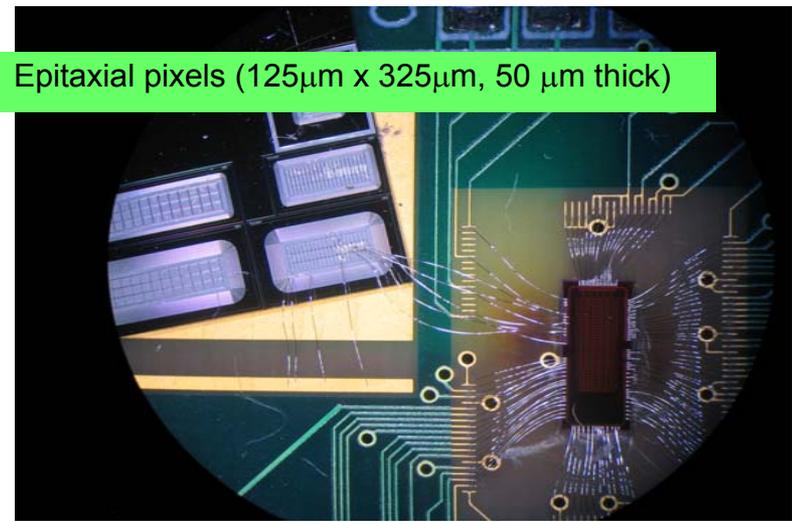
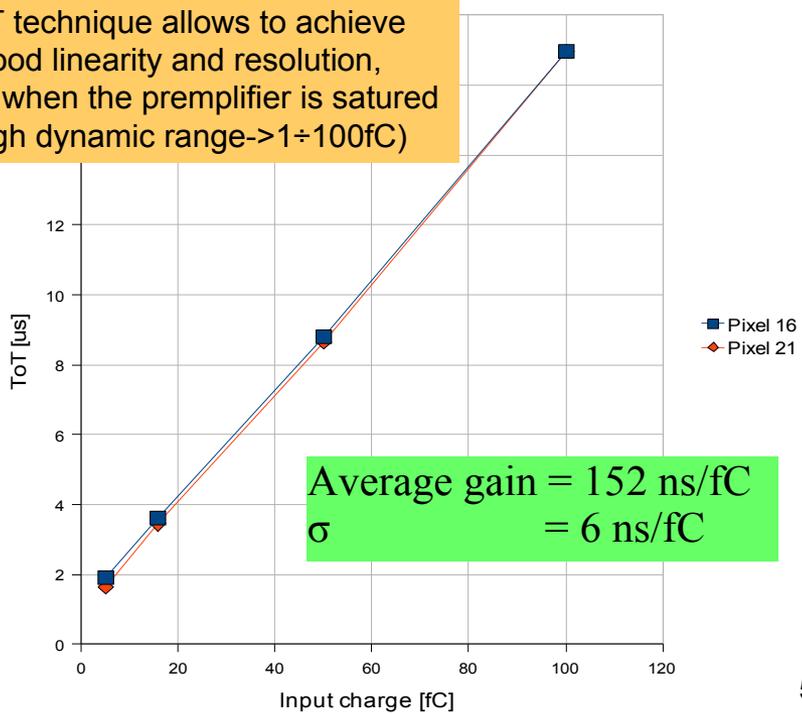


- 5x2 mm<sup>2</sup> area with 4 folded columns with a total of 320 readout cells of 100x100μm<sup>2</sup> size
- analogue + digital circuits (analog power consumption below 12μW @1.2V)
- Clock @ 50MHz
- Time over Threshold technique implemented to obtain a energy loss measurement
- SEU-hardened memory cells (Dice with baseline design: all pmos devices are located in the same nWell and don't have guard contact separation)
- absence of enclosed structures to study the radiation tolerance of the 130nm CMOS technology
- inputs for connecting external sensors (selectable input polarity)
- comparator threshold controlled by DAC (5 bits)
- 12 + 12 bits leading and trailing edge and 12 bits configuration registers
- 12 bits bus for time stamp and 12+7 bits output bus for data + address



# Characterization of ToPix\_2

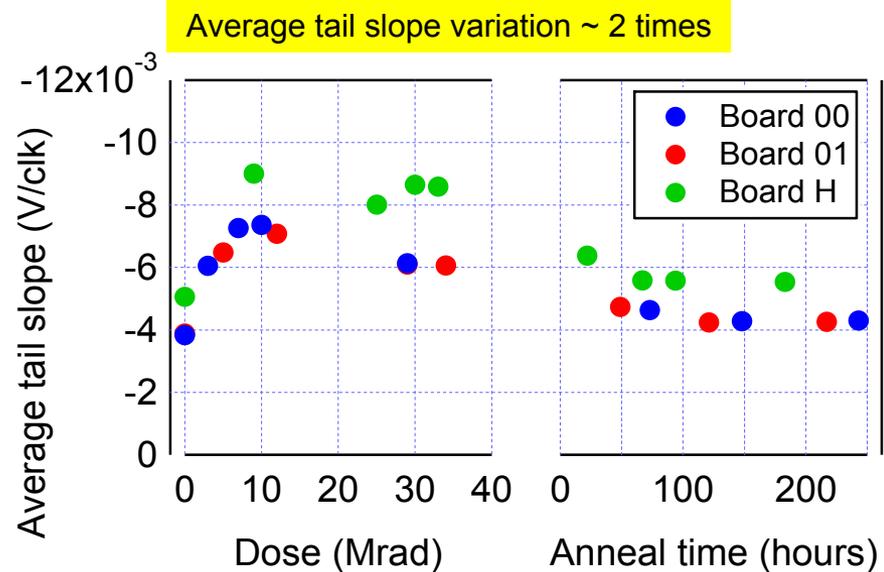
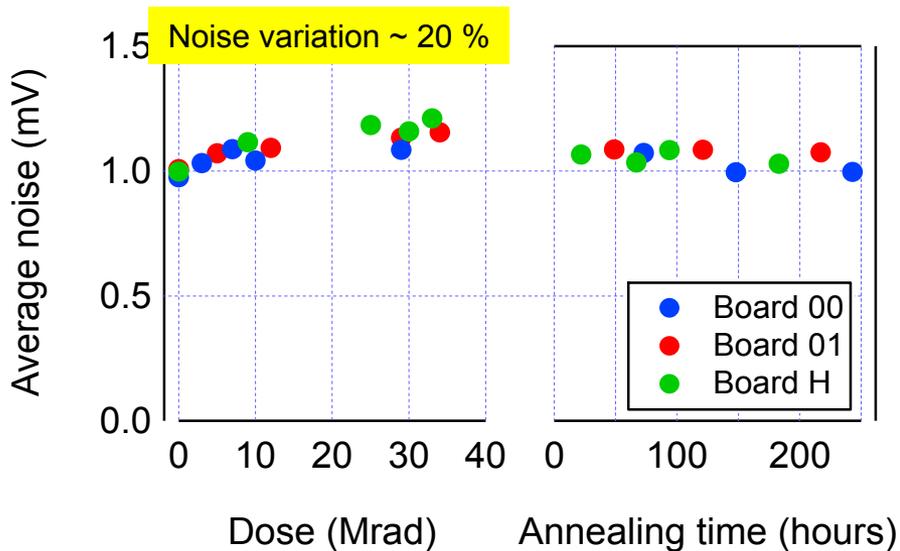
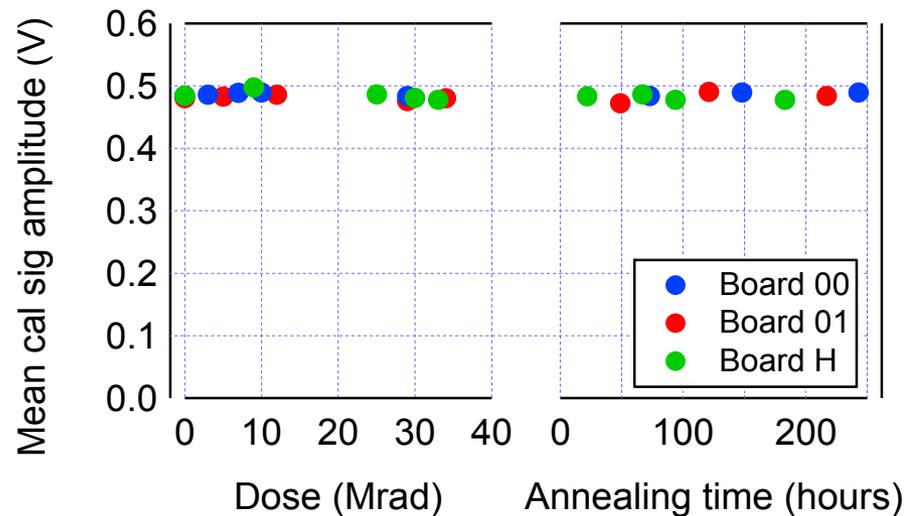
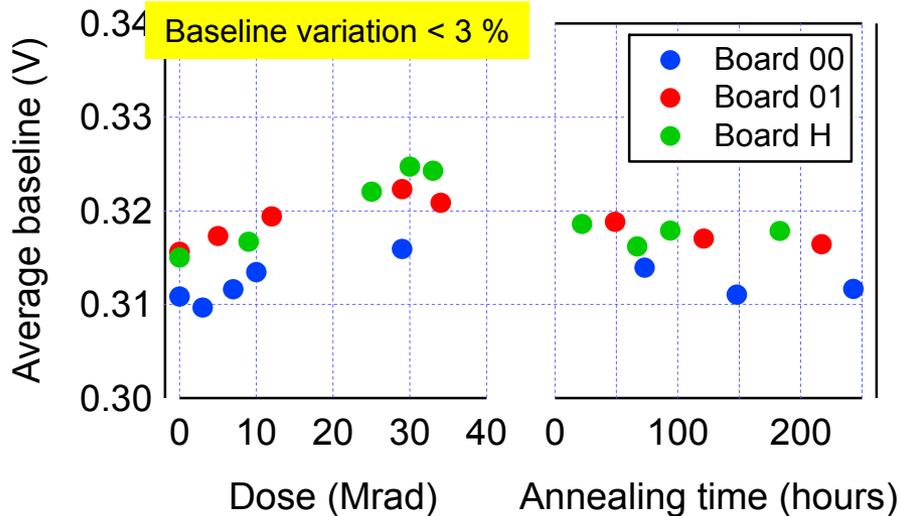
ToT technique allows to achieve good linearity and resolution, even when the preamplifier is saturated (high dynamic range-> $1 \div 100 \text{fC}$ )



TOT calibration

# TID test on ToPix\_2

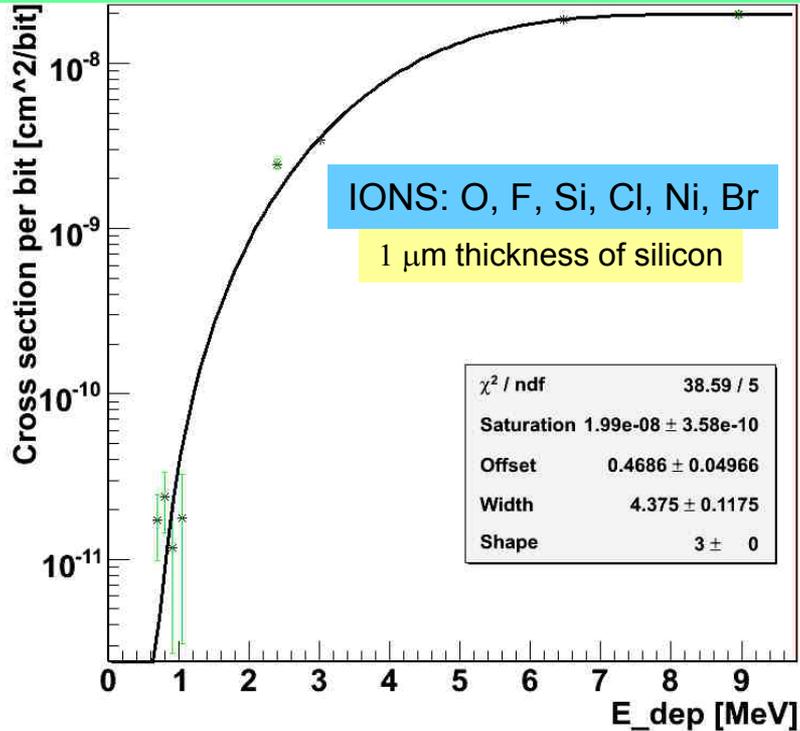
Total Ionizing Dose test with the X ray source at CERN (Thanks to F. Faccio)  
followed by an annealing phase at 100°C



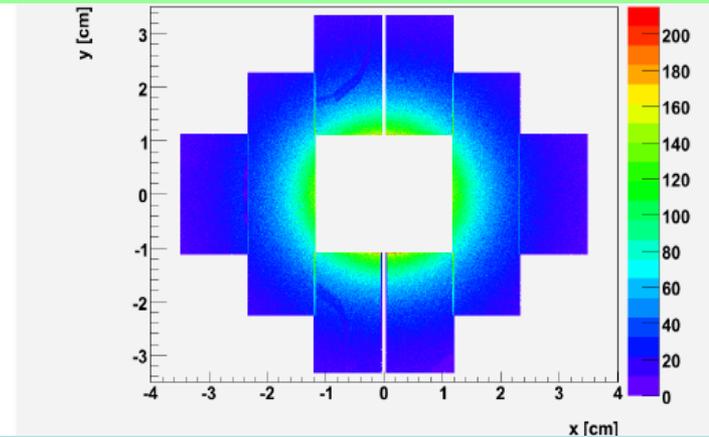
# SEU test on ToPix\_2

12 bit configuration register made by SEU-hardened memory cells based on first Dice architecture (all pmos devices are located in the same nWell and don't have guard contact separation)

SEU cross section of ToPix2 for heavy ions. The test was performed at the SIRAD facility (INFN-LNL). Thanks to A. Candelori



And using the method described in the paper of M. Huhtinen, F. Faccio - CERN  
“Computational method to estimate SEU rates in an accelerator environment”; NIM A 450 (2000) 155-172

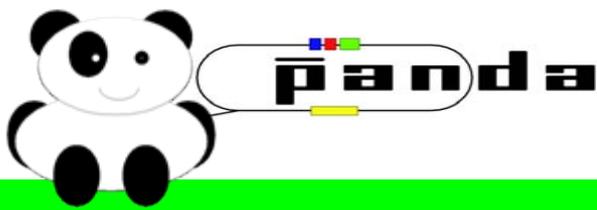


Hadron flux on the disk 2 of the pixel detector, evaluated for pbar-p interactions @15 GeV/c:  
5.8 [Mhit / (s·cm<sup>2</sup>)]

In the PANDA environment:  
4.1·10<sup>-9</sup> SEU/s·bit  
(evaluated with a 1μm<sup>3</sup> sensitive volume)

2.3 SEU / hour are expected in the final ToPix readout chip taking into account:

- ✓ a 12 bit configuration register in each pixel readout cell with the same DICE architecture
- ✓ 12760 pixel readout cells



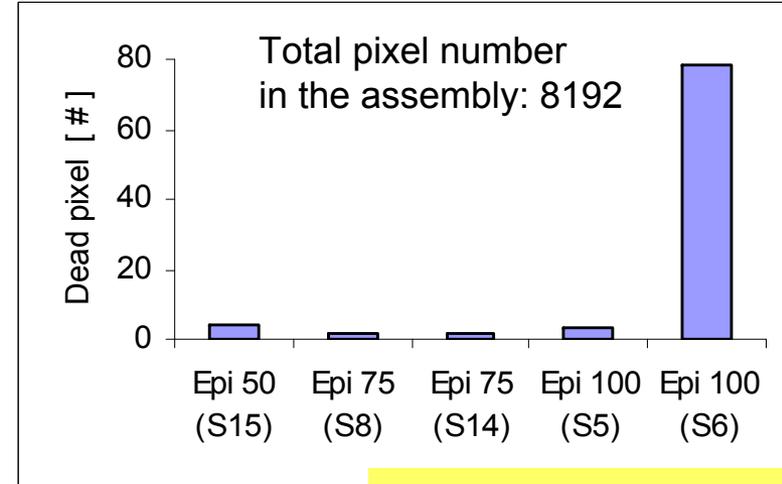
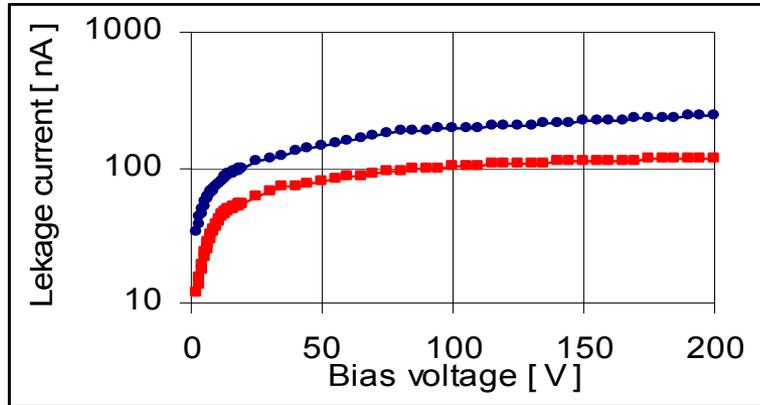
# Conclusions

- ❖ the carbon foam is an interesting material for the power dissipation of the pixel detector
  
- ❖ the use of epitaxial silicon material could be very promising, also in term of radiation damage, but an epitaxial resistivity tuning has to be performed for the full depletion voltage optimization
  
- ❖ the 130 nm CMOS technology is suitable to develop the pixel readout for:
  - ❖ limited power consumption
  - ❖ smaller pixel with many functionalities, but
    - ❖ enclosed gate layout is needed for the critical transistors of the discharge circuit or larger current is needed from the capacitor discharge circuit
    - ❖ the implemented DICE architecture (first level of radiation hardness) isn't completely satisfactory for the PANDA environment

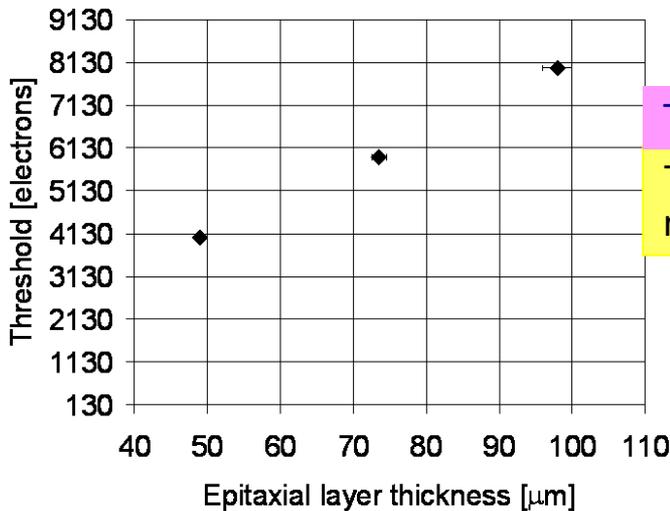
# Results from thin Si-epitaxial pixel assemblies

Epi 75 and Epi 50

Test performed with a  $^{90}\text{Sr}$  source to verify the bump bonding process



Dead pixel %  $\leq 0.05\%$ ;  
 $\leq 1\%$  (worst case)



Test performed with a  $^{90}\text{Sr}$  source

Threshold values in electrons corresponding to the Landau most probable value for the different epitaxial layer thicknesses